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Instruments and Technology*

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## **Optoelectronic Measurement Technology and Systems**

**Jigui Zhu  
Kexin Xu  
Hai Xiao  
Sen Han**  
*Editors*

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## Introduction

With the deepening and intensification of information, a wider range of information sources and acquisition methods have become the basis for societal development. Because of its large capacity, high efficiency and high precision, optoelectronic measurement technology has become the main means of information sensing and acquisition. It has and will continue to play an important role in important fields such as consumer electronics, industrial manufacturing, environmental protection, and scientific research.

The optoelectronic measurement research covers a rich variety of content including lots of areas from scientific research, manufacturing industry, to daily life and the scope will continue to be expanded and the content to be more and more in-depth. On one hand, traditional optoelectronic measurement research and application represented by the background of industrial measurement and optoelectronic detection have been constantly improved and concerned performances have been constantly improved as well. On the other hand, the needs of optoelectronic measurement represented by the optical interferometry and optical dynamic measurement have been emerging ceaselessly, as well as the continued development of measuring methods and applications.

More than 60 manuscripts have been accepted (2 invited manuscripts and 21 oral presentations) in the branch of OIT 2019—Optoelectronic Measurement Technology and Systems, ranging many research fields including optoelectronic measurement, optical instruments, industrial metrology, optical interferometry, optical fiber sensing, etc. These manuscripts appropriately reflect the current focusing problems and research level of the optoelectronic measurement field.

**Jigui Zhu**  
**Kexin Xu**  
**Hai Xiao**  
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